

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re Patent Application of:

Osamu NAKAMURA et al.

Serial No. 10/066,542

Filed: February 5, 2002

For: SEMICONDUCTOR DEVICE AND

METHOD FOR MANUFACTURING

THE SAME



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) Art Unit: Unknown

) Examiner: Unknown

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**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents and Trademarks  
Washington, D.C. 20231

Sir:

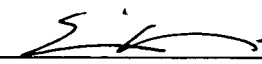
In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99, it is requested that the references listed on the attached Form PTO-1449 be made of record in the above-identified application. Copies of the references are submitted herewith in accordance with 37 C.F.R. 1.98(a).

The Examiner's attention is particularly directed to JP 05-109737, which discloses a gettering by using argon gas.

The documents are being submitted within 3 months of the filing, or entry into the national phase, of this application or before the first Office Action on the merits, whichever is later, therefore no fee or certification is required under 37 C.F.R. § 1.97(b).

The Commissioner is hereby authorized to charge fees under 37 C.F.R. §§1.16, 1.17, 1.20(a), 1.20(b), 1.20(c), and 1.20(d) (except the Issue Fee) which may be required now or hereafter, or credit any overpayment to Deposit Account No. 19-2380 (740756-2431).

Respectfully submitted,

  
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